

FIG. 1A

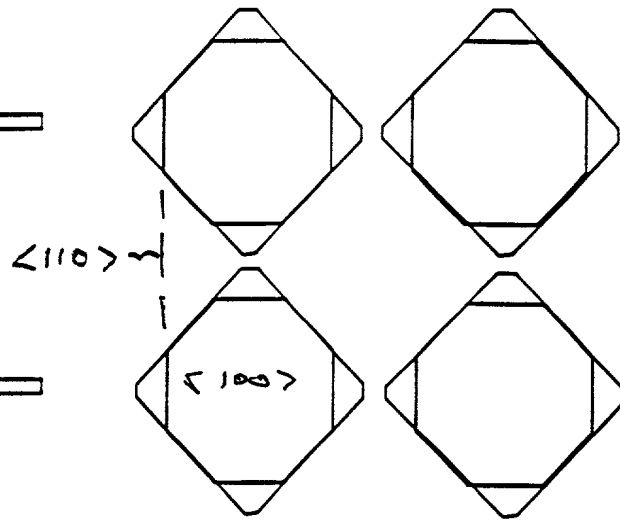


FIG. 1B

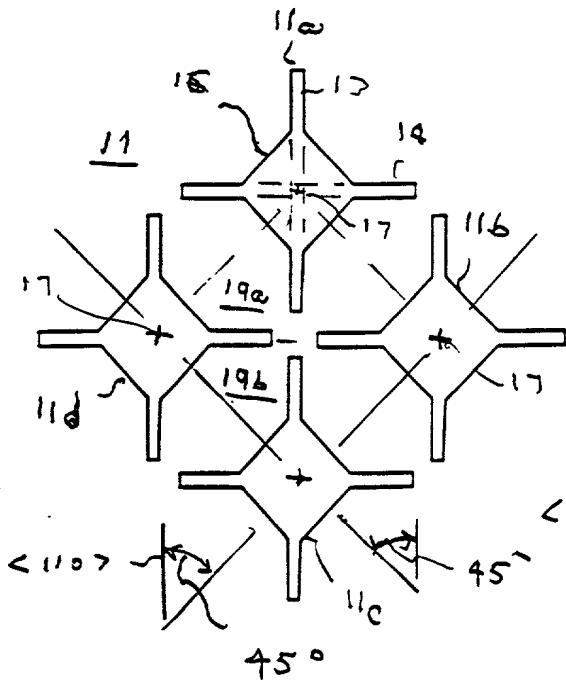


FIG. 2A

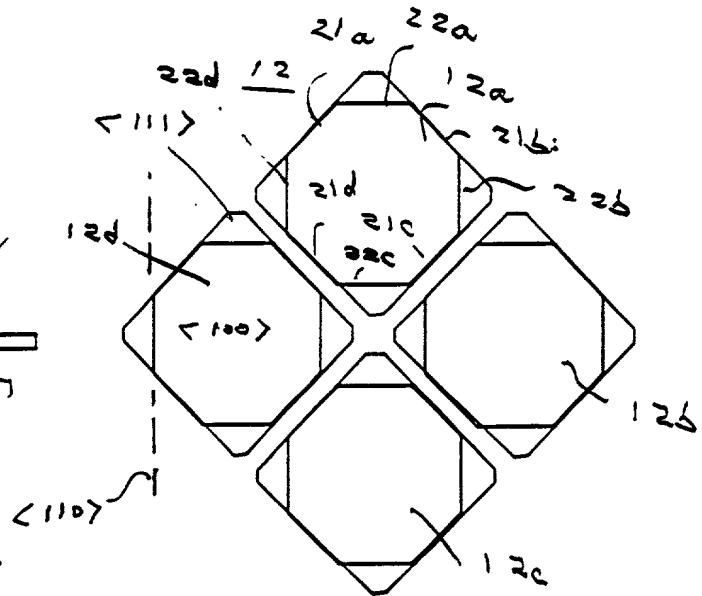


FIG. 2B

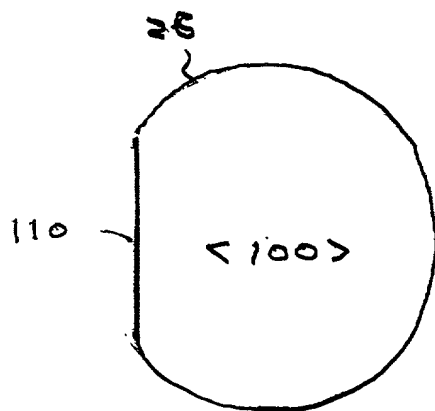
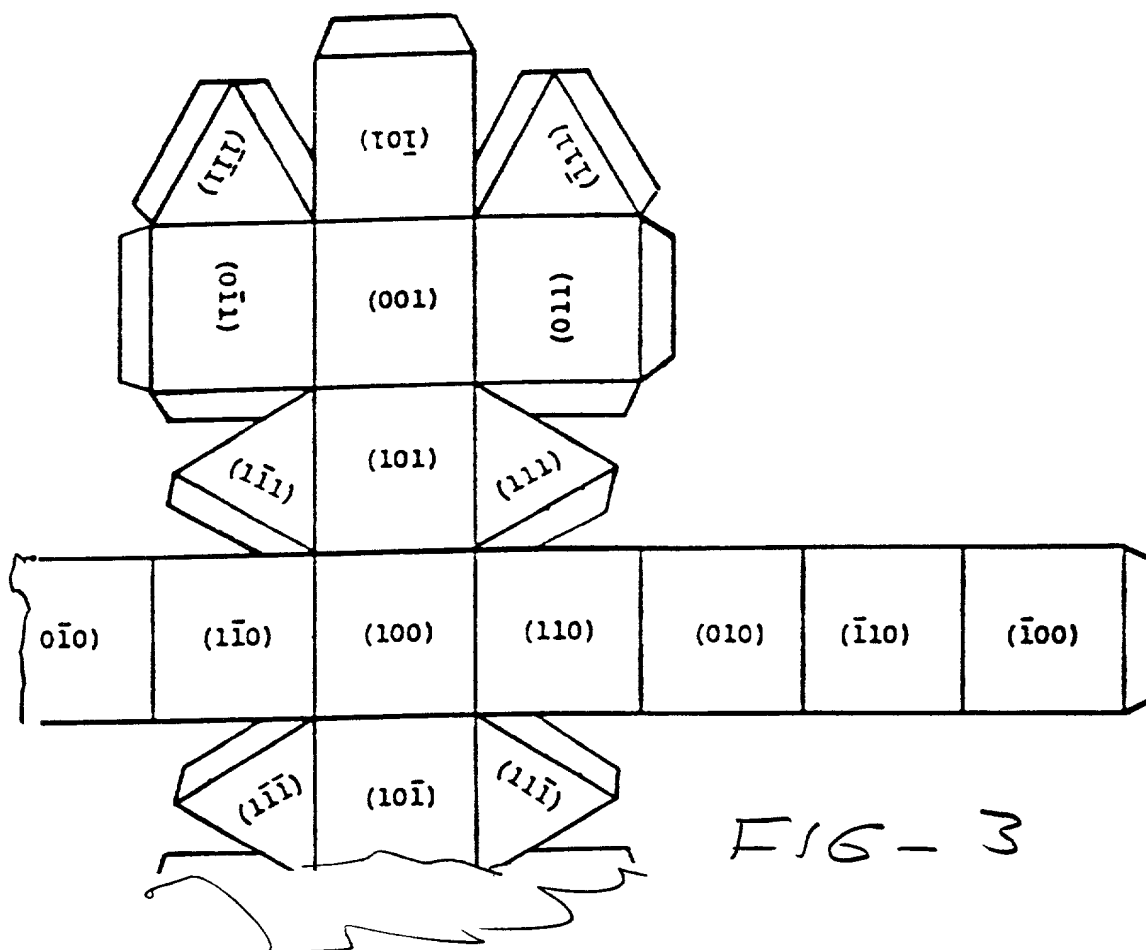
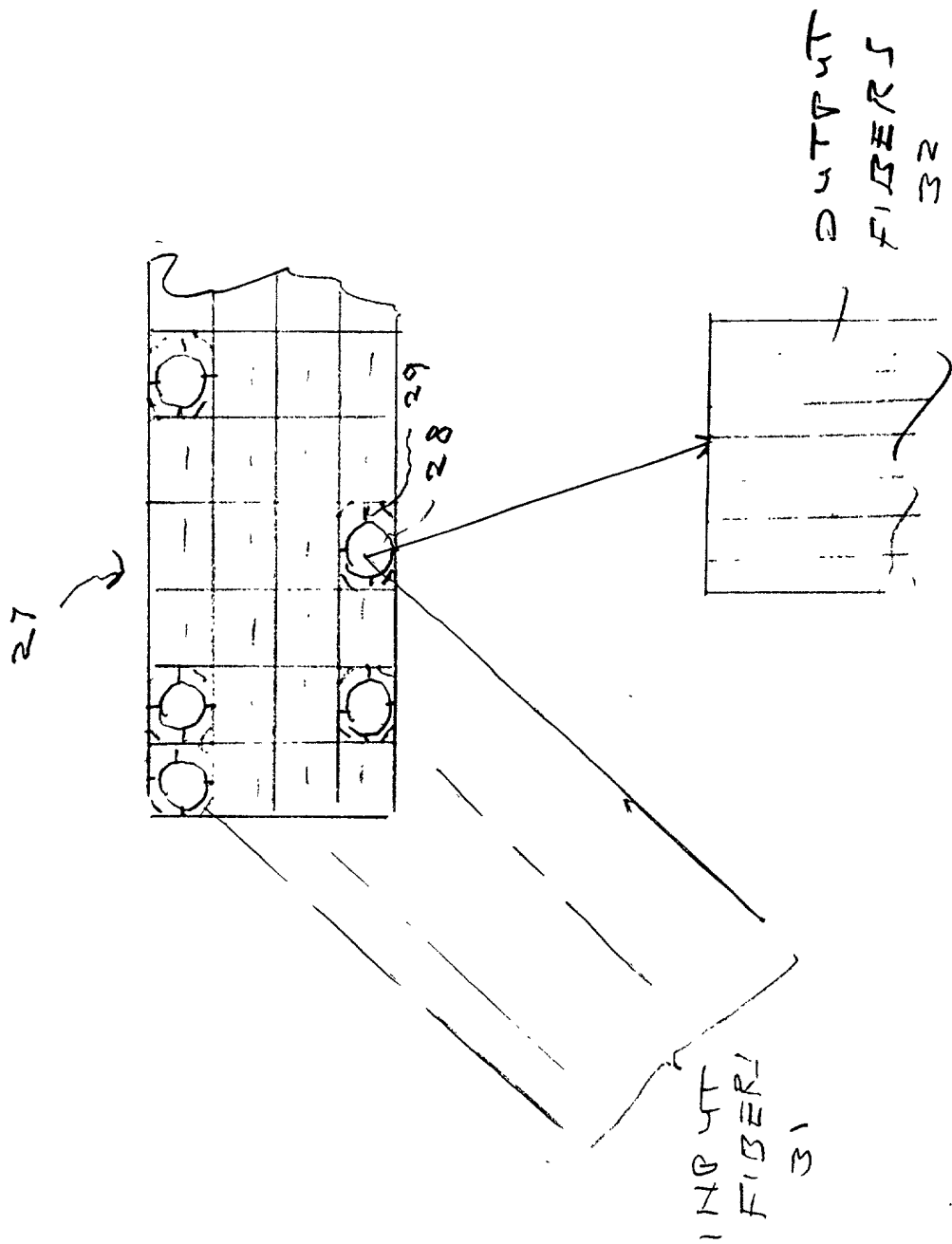


FIG-4



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33 -

Providing a semiconductor crystal substrate with a $\langle 100 \rangle$ surface relatively horizontal for placement of a mask and having an alignment feature on the perpendicular $\langle 110 \rangle$ crystal plane

34 -

Providing a mask with cross arms and a centered diamond with the diamond centers lying on a line offset from the $\langle 110 \rangle$ plane by 45 degrees when the mask is placed in the etching position

36 -

Doing a KOH etch to provide an array of membranes each being defined by an octagon with four of the sides being a vertical etch back in the $\langle 100 \rangle$ plane and the alternating other four sides being defined by a $\langle 100 \rangle$ axis seeking etch

37 -

Etching suspended circular and steerable mirrors in each octagon membrane to provide an N by N optical switch

FIG. 6